



## [ThF1] Carbon Neutrality in Semiconductor Industry I

<b>Session Date</b>	November 13 (Thu.), 2025
<b>Session Time</b>	09:00-10:35
<b>Session Room</b>	Room F (Panorama Room, 16F)
<b>Session Chair</b>	Prof. Hongsik Jeong (UNIST, Korea)

### [ThF1-1] [Plenary]

09:00-09:45

#### **Advances in Etching Technologies for Next Generation Semiconductor Manufacturing towards Sustainable Development Goals**

Shih-Nan Hsiao (Nagoya Univ., Japan)

### [ThF1-2] [Invited]

09:45-10:10

#### **Estimating GWP based on a Comprehensive Analysis of R134a: A Method for Accurate Monitoring of Greenhouse Gas Emissions**

Dongkyum Kim, Sang Woo Kim, Miyeon Park, and Jeongsoon Lee (KRISS, Korea)

### [ThF1-3] [Invited]

10:10-10:35

#### **Development of NF<sub>3</sub> Alternative Gas for Global Warming Potential Reduction**

Wontae Noh, Woongbin Yim, Soo Namgoong, Sukhyun Hong, Sung Ryong Moon, Sangmin Lee, and Young Chul Choi (Wonik IPS, Korea)